

Amendments to the Claims

Claim 1 (Currently Amended) A semiconductor device comprising:
a substrate including an integrated circuit;
an interlayer insulating layer formed on said substrate, said interlayer insulating layer having a contact hole;
a ferroelectric capacitor formed by a first electrode layer, a ferroelectric layer and a second electrode layer deposited on said interlayer insulating layer in this order;
a wiring layer electrically connecting said second electrode layer of said ferroelectric capacitor to said integrated circuit through a said contact hole in said interlayer insulating layer; and
an insulating side wall film covering a peripheral section of said ferroelectric capacitor electrically insulating said peripheral section of said ferroelectric capacitor from said wiring layer, and being spaced from a peripheral edge section of said contact hole.

Claim 2 (Currently Amended) The semiconductor device according to the claim 1, wherein said integrated circuit wiring layer includes a contact plug within said contact hole and said wiring layer electrically connects to said contact plug.

Claim 3 (Currently Amended) The semiconductor device according to the claim 2, wherein said interlayer insulating layer includes a plug oxidation protective film consisting of comprising silicon nitride –and silicon oxide–, and said ferroelectric capacitor is mounted on said interlayer insulating layer.

Claim 4 (Previously Presented) The semiconductor device according to the claim 1, wherein said insulating side wall film includes a hydrogen diffusion preventing layer.

Claim 5 (Currently Amended) The semiconductor device according to the claim 1, wherein said ferroelectric layer-consists of comprises bismuth strontium tantalate.

Claims 6-11 (Cancelled)

Claim 12 (New) The semiconductor device according to claim 1, wherein at least a portion of said wiring layer is deposited on said insulating side wall film.

Claim 13 (New) The semiconductor device according to claim 1, wherein an upper surface of said second electrode layer is free of said insulating side wall film.